



Att'y. Dkt. No. AMAT/3771 Y1/DSM/LOW K/JW

in re Application of:
Mandal

Serial No.: 10/091,699

Confirmation No.: 7928

Filed: March 4, 2002

For: **VERY LOW DIELECTRIC
CONSTANT PLASMA-
ENHANCED CVD FILMS**

Group Art Unit: 2814

Examiner: Rao, Shrinivas H.

MAIL STOP RCE
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

CERTIFICATE UNDER 37 CFR 1.10

I hereby certify that this correspondence and the documents referred to as attached therein are being deposited on May 20, 2003 with the United States Postal Service in an envelope as "Express Mail Post Office to Addressee," mailing label No. EV349852695US addressed to: MAIL STOP RCE, Commissioner for Patents, P.O. Box 1450 Alexandria, VA 22313-1450.

5/20/03

Date _____

Wendy A. Parker
Signature

PRELIMINARY AMENDMENT

In response to the Final Office Action dated February 26, 2003, having a shortened statutory period for response set to expire on May 26, 2003, please enter this response and reconsider the claims pending in the application for reasons discussed below. Although Applicant believes that no fee is due in connection with this response, the Commissioner is hereby authorized to charge counsel's Deposit Account No. 20-0782/AMAT/3771.Y1/KMT for any fees, including extension of time fees or excess claim fees, required to make this response timely and acceptable to the Office.

IN THE CLAIMS:

Please cancel claims 2-4, 9-15, and 17 without prejudice and amend the claims as follows:

1. (Amended) A method for depositing a low dielectric constant film, comprising:

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TECHNOLOGY CENTER 2800
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